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## 13.5nm, 25.4mm Dia, 5° AOI, EUV Spherical Mirror



TECHSPEC® Extreme Ultraviolet (EUV) Spherical Mirrors

Stock **#11-730** **20+ In Stock**

MRP ₹4,34,836

**Price inclusive of all taxes**

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### General

Spherical Mirror **Type:**

### Physical & Mechanical Properties

25.40 +0.00/-0.13 **Diameter (mm):**

6.35 ±0.25 **Thickness (mm):**

<3 RMS **Surface Roughness (□):**

## Optical Properties

Metal/Semiconductor **Coating Type:**

Mb/Si Multilayer **Coating:**  
Top Layer: Silicon

M10 @ 632.8nm **Surface Flatness (P-V):**

13.5 **Design Wavelength DWL (nm):**

250.00 **Effective Focal Length EFL (mm):**

**Fused Silica** (Corning 7980) **Substrate:** □

5 **Angle of Incidence (°):**

R<sub>abs</sub> >60% @ 13.5nm **Coating Specification:**

500.00 **Radius R<sub>1</sub> (mm):**

500.00 **Radius of Curvature (mm):**

0.50 **Full Width-Half Max FWHM (nm):**

## Regulatory Compliance

[View](#) **Certificate of Conformance:**

United States **Country of Origin:**

**Imported By:**  
Edmund Optics India Private Limited  
267, Greystone Building, Second Floor,  
6th Cross Rd, Binnamangala,  
Stage 1, Indiranagar, Bengaluru,  
Karnataka, India 560038  
Phone: +91- 80-6845 0000

## Product Details

- Mb/Si Multilayer Coating on Super-Polished Substrates
- Maximum Achievable Reflection at 13.5nm
- Designed for EUV Beam Focusing Applications
- Narrow Pass Band for HHG Applications

Extreme Ultraviolet (EUV) Spherical Mirrors feature a multilayer Mb/Si coating providing greater than 60% reflection at 13.5nm. They are designed for a 5° angle of incidence and intended for focusing unpolarized EUV laser sources. A surface roughness of less than 3□ RMS minimizes scatter. This is essential for EUV wavelengths which experience more scattering than longer wavelengths. EUV Spherical Mirrors have a very narrow pass band of approximately 0.5nm, ensuring that only the 13.5nm harmonic of interest is reflected in high harmonic generation (HHG) applications. [Typical applications](#) for EUV spherical mirrors include Coherent Diffractive Imaging (CDI), EUV imaging, and EUV nanomachining.

**Note:** Test data from each mirror's production run sample included.